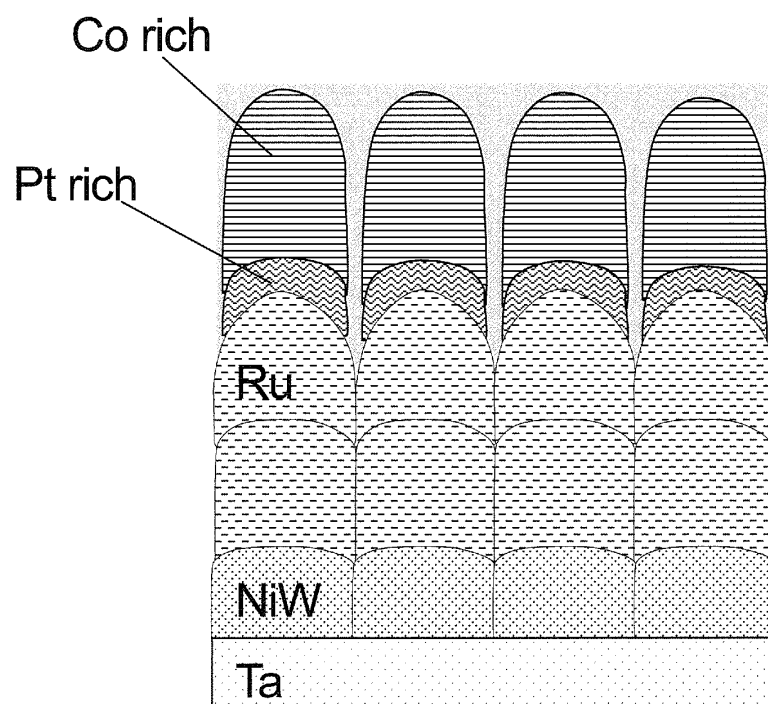
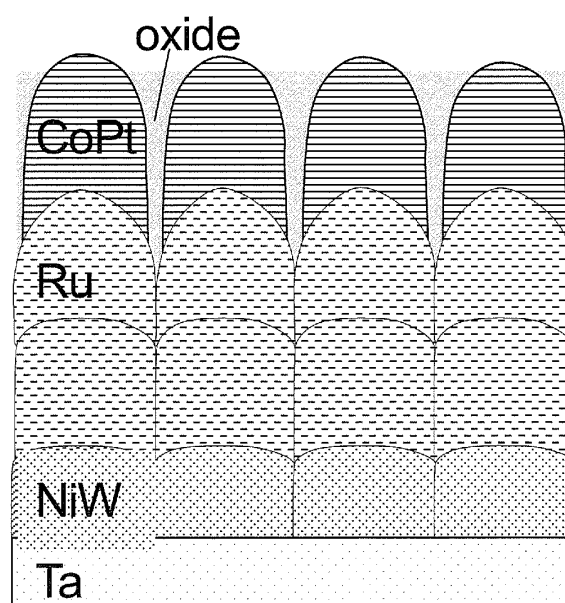


[図1]



[図2]



[図3-A]

層構成	膜厚
C	7 nm
Co-rich Magnetic layer	0.5 - 16 nm
Pt-rich Buffer layer	0 - 2.5 nm
Ru Under layer 2	10 nm
Ru Under layer 1	10 nm
Ni90W10	6 nm
Ta	5 nm
Glass	

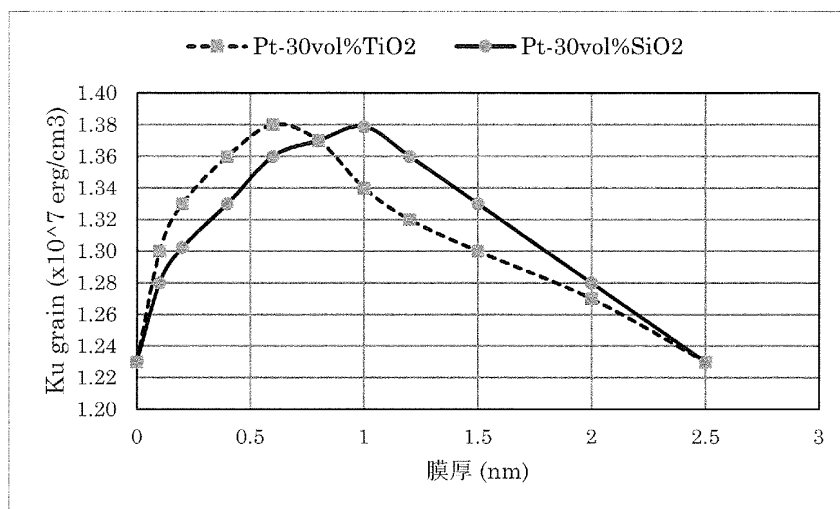
[図3-B]

層構成	膜厚
C	7 nm
Pt-rich Buffer layer	0 - 2.6 nm
Co-rich Magnetic layer	0.5 - 16 nm
Ru Under layer 2	10 nm
Ru Under layer 1	10 nm
Ni90W10	6 nm
Ta	5 nm
Glass	

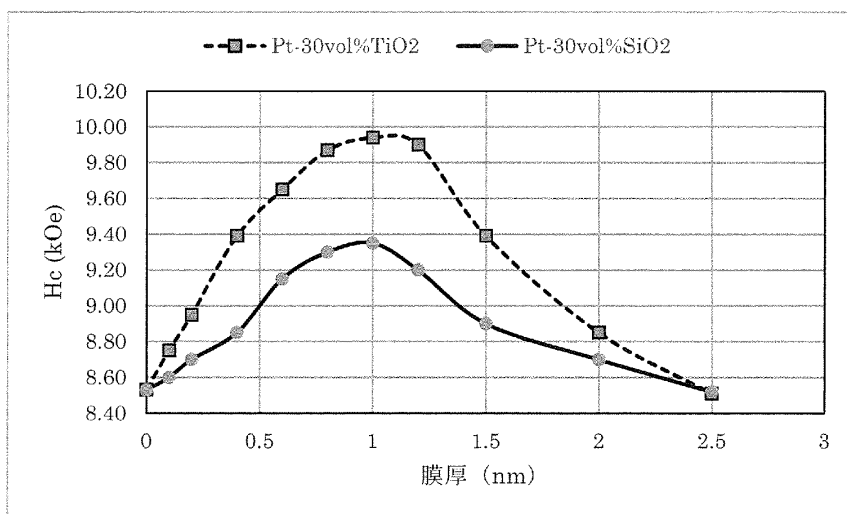
[図3-C]

層構成	膜厚
C	7 nm
Pt-rich Buffer layer 4	0 - 0.8 nm
Co-rich Magnetic layer 4	4 nm
Pt-rich Buffer layer 3	0 - 0.8 nm
Co-rich Magnetic layer 3	4 nm
Pt-rich Buffer layer 2	0 - 0.8 nm
Co-rich Magnetic layer 2	4 nm
Pt-rich Buffer layer 1	0 - 0.8 nm
Co-rich Magnetic layer 1	4 nm
Ru Under layer 2	10 nm
Ru Under layer 1	10 nm
Ni90W10	6 nm
Ta	5 nm
Glass	

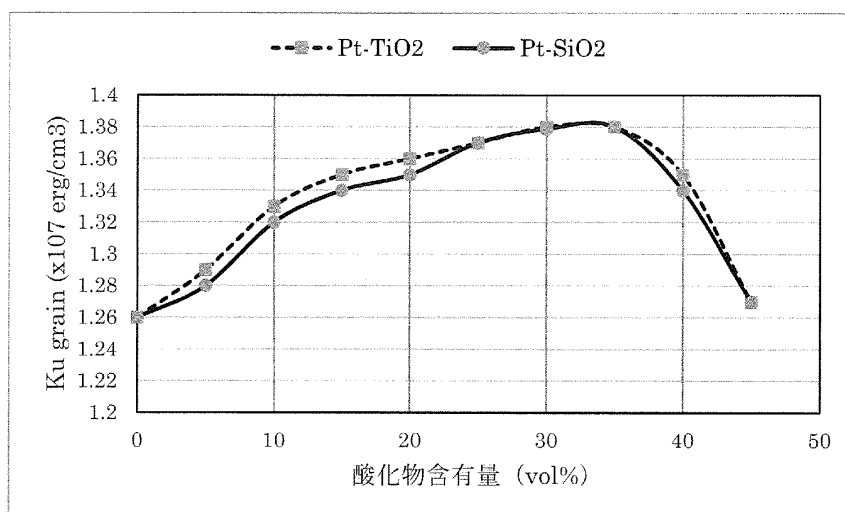
[図4]



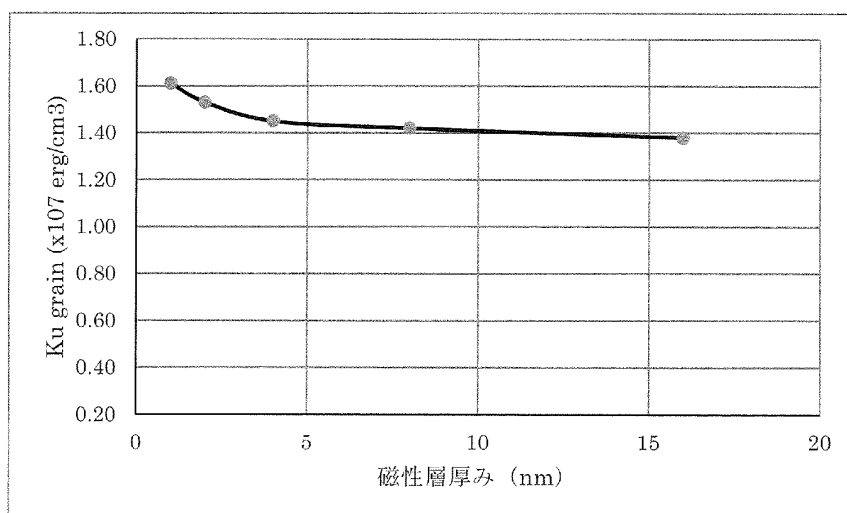
[図5]



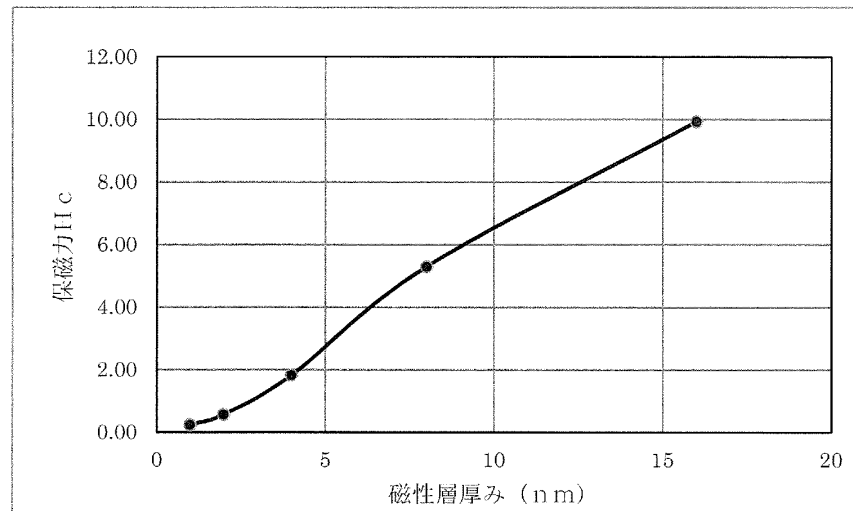
【図6】



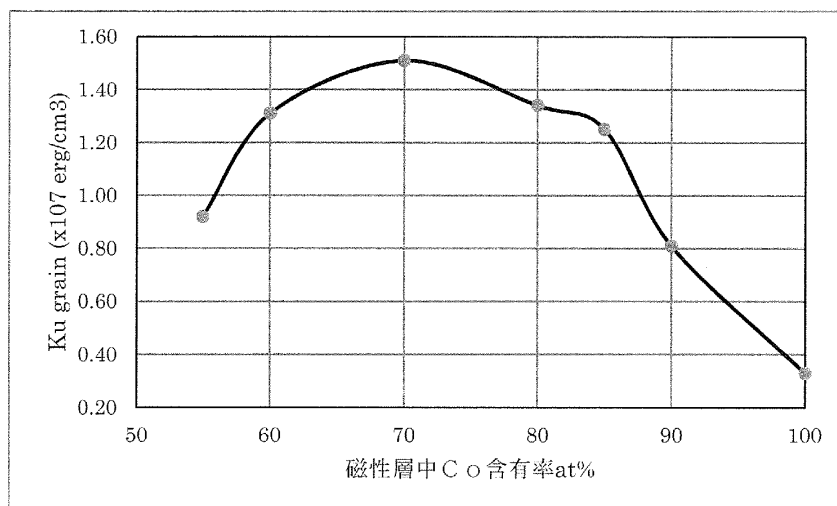
【図7】



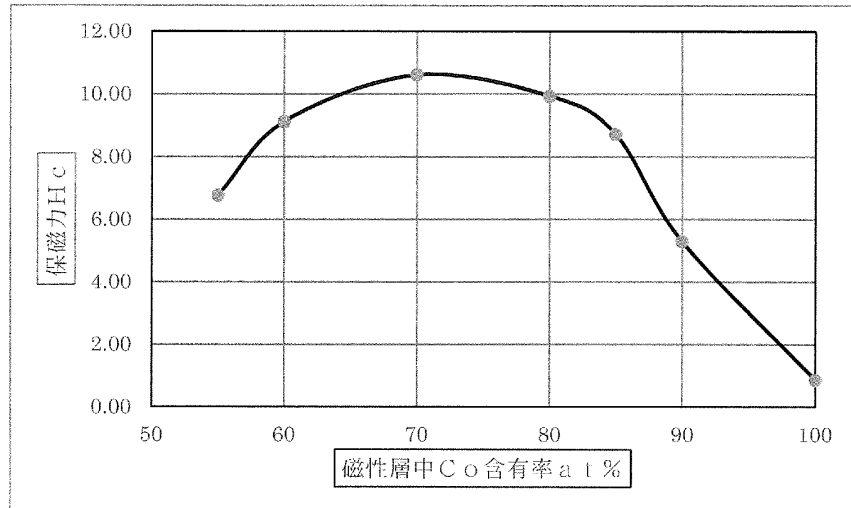
[図8]



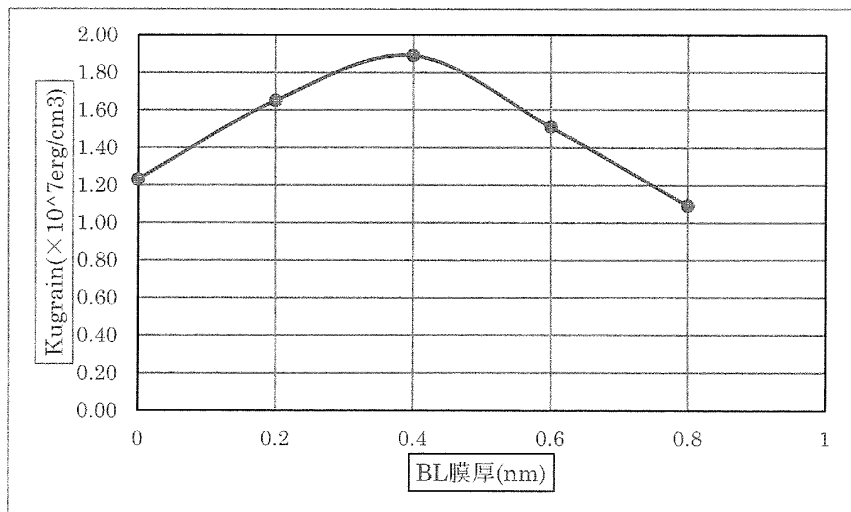
[図9]



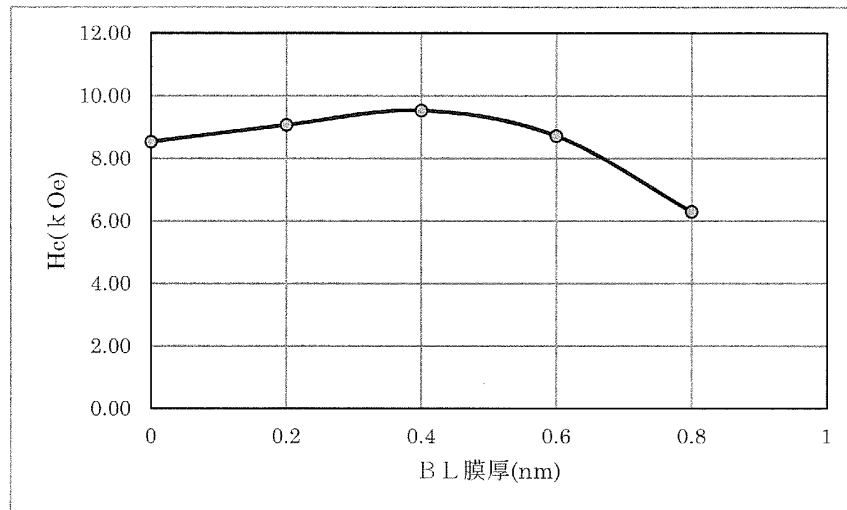
[図10]



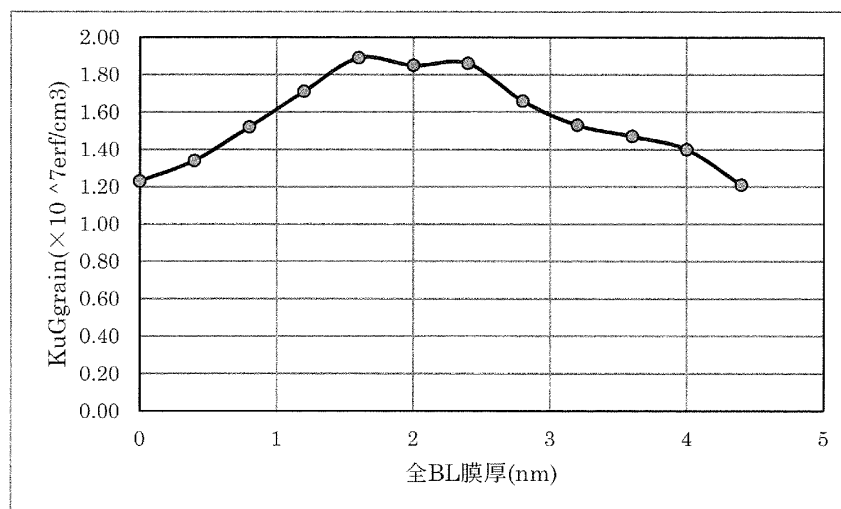
[図11]



[図12]



[図13]



[図14]

